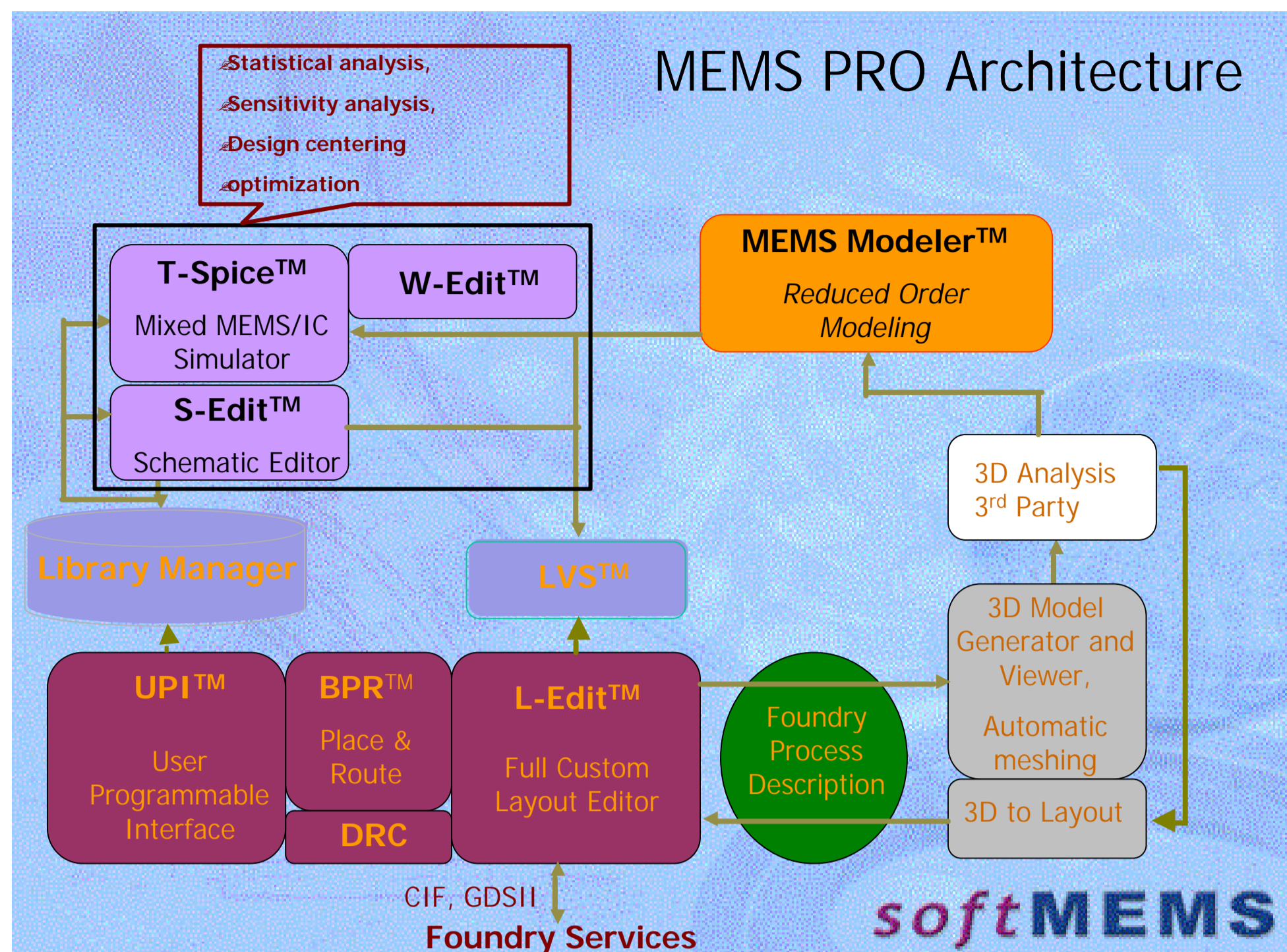


An illustrated approach to DfM for MEMS by *softMEMS*



Design for Manufacturing Tools through the design flow :

- Schematic level / parameterized behavioral modeling level :
 - Monte Carlo analysis, sensitivity analysis, optimization (including IC design if necessary)
- Layout :
 - Test structures libraries
 - Design verification (DRC, LVS)
- 3d model generation
 - Cross section view and 3D inspection
 - Quick generation of geometry and meshing allows faster multi-simulations tasks
 - Model reduction for system level simulations

SENSITIVITY ANALYSIS :

- Sensitivity calculation: parameters contribution to performance
- Sensitivity analysis is performed to investigate influence of individual parameters on the device behavior
- Easy set up : parameter sweep simulations
- May help designers to indicate to foundry what process parameters must be closely watched
- MEMS and IC models to take into account all process variations on :
 - Material properties,
 - Thermal coefficients,
 - Etch rate ratios, over-etch variations.

Combined MEMS & IC Schematics

- Schematics can contain both IC and MEMS modules
 - IC modeled using standard IC models
 - MEMS modeled using behavioral macro models
- Component library
 - Behavioral models for standard MEMS components
- Simulation of MEMS Macromodels at ODE Level
- Model Representation
 - Equivalent Circuit Models
 - Functional Models
 - Table Based Models
- Transient/DC/AC Analysis
- Parametric Analysis

Statistical Analysis

- Statistical analysis based on process/mask variations
 - Incorporates statistical data from foundries into models
 - Develop process corners for simulation
 - Monte Carlo analysis

Optimization

Example: Optimize springlength using minimum area with resonant frequency = 30 KHz

Basic Bricks at the Layout Level

- Design Rules Checking
- Parameters and Parasitic Extractions
- Layout Versus Schematic
- 3D Modeling

Verification- Extraction

```

* Project EXAMPLE3, FILE2
* INCLUDE 'MODELS.SPC'
M1 1 2 3 4 PSS L=2 W=5
M3 1 2 3 4 PSS L=2 W=5
M10 4 5 6 4 PSS L=2 W=5
M11 5 7 3 4 PSS L=2 W=5
M12 8 7 2 4 PSS L=2 W=5
C1 0 4 12pF
.END
    
```

Extract

- Extraction produces a multi-domain netlist of listing of MEMS devices and their connections
- Device is accompanied by listing of relevant parameters- geometry or higher level - C, N of, Comb fingers etc.
- Extraction also produces a set of lumped parasitic elements - capacitances and resistances on each signal or control line
- Values are computed from the geometry and process variables- layer thickness and dielectric constants

DRC- Design Rule Checking

- DRC set up to check manufacturing rules, spacing, surround, size, etc.
- Supports context sensitive rules- e.g. Number of etch holes per area on plates necessary to make sure plate is released.
- Supports device specific rules e.g. placement of stator over ground plane on motor